



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

17/B
P. Ullrich
8-8-03

Re Patent Application of:

Yoshihiro MORI et al.

Serial No. 09/942,038

Filed: August 30, 2001

For: A METHOD FOR FABRICATING
SEMICONDUCTOR DEVICE INCLUDING
ANNEALING AN ELECTRODE IN A
REDUCING ATMOSPHERE BEFORE
CAPACITOR INSULATING FILM FORMING
(AS AMENDED)

)
) Group Art Unit: 2813
) Examiner: Yen-nhu B. Huynh
) Confirmation No.
) Date: July 18, 2003
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CERTIFICATE OF MAILING OR TRANSMISSION
[37 CFR 1.8(a)]

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Signature: _____

Name: Jeannie Saxton

AMENDMENT

Mail Stop _____
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the Examiner's Office Action mailed February 28, 2003, the due date for which having been extended two months (2) to July 28, 2003, please consider the following amendments and remarks in connection with the above-identified application.

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IN THE TITLE:

Please change the title of the present application to read as follows:

“A METHOD FOR FABRICATING SEMICONDUCTOR DEVICE INCLUDING ANNEALING AN ELECTRODE IN A REDUCING ATMOSPHERE BEFORE CAPACITOR INSULATING FILM FORMING”.